

AMICUS









A COMPACT, VERSATILE XPS INSTRUMENT DESIGNED FOR A WIDE RANGE OF APPLICATIONS





Non-dispersive energy analyser of the AMICUS electron spectrometer

The AMICUS instrument has been developed from proven technology and incorporates the latest in digital control electronics producing an easy to use, flexible system suitable for all levels of expertise.

The AMICUS XPS instrument has been designed with a compact footprint enabling it to be used for a wide range of applications from routine laboratory use to quality control and assurance in production environments.

The compact design has been accomplished through the incorporation of the successful `Dupont' type analyser and optimised digital electronics.

A simple, rapid sample introduction system has been incorporated with a fully automated multi-sample carousel system to allow a wide range of applications to be addressed including unattended operation. The standard highly user friendly XPS acquisition and data processing software package allows simple and complex studies to be carried out in a totally automated fashion. The ability to set up and store previously defined data acquisition parameters ensures reproducible procedures can be obtained, an important criterion in quality control environments.

ROUTINE XPS ANALYSIS

The high efficiency energy dispersive analyser of the AMICUS means that a high sample throughput can be obtained. Even valence band spectroscopy is possible in a matter of minutes. In this example two hydrocarbon polymers, polystyrene and polyethylene were examined. Analysis of the C 1s core level reveals only minor differences. The valence band spectra (right) show that each polymer has a characteristic "fingerprint" associated with subtle changes in bonding of the valence electrons of the C 2p and C 2s levels allowing easy identification.

PROCESS CONTROL -ANALYSIS OF PALLADIUM CATALYSTS

Many industrial processes rely upon the surface chemical properties of materials. The performance of Pd based catalysts for example is directly related to their surface properties. Pd pellets have been taken from the reaction vessel at various stages of their active lifetime. As the lifetime increases activity decreases, XPS analysis of the Pd 3d core level reveals a gradual dominance of the surface oxide. Regeneration can reactivate the Pd pellet via reduction of the oxidised surface as shown by sample E. The AMICUS is ideally suited to this type of analysis due to the fully automated batch analysis capability.

A:	Fresh
В:	Used (active)
C:	Used (activity lowered)
D:	Deteriorated
E:	Regenerated

QUALITY CONTROL -CHEMICAL STATE PROFILING

Combining XPS analysis with the ion sputter gun of the AMICUS can provide depth dependent chemical state information. Here two Si samples were heat treated for 2 min (Sample A) and 15 min (Sample B) respectively in an oxidising atmosphere. The powerful data interpretation facilities available enable an oxide and metallic Si component to be extracted from the Si 2p feature and then plotted as a function of depth. It is clear that the SiO₂/Si interface has extended from ~10 nm to ~15 nm with the prolonged heat treatment.















QUALITY XPS

INSTRUMENTATION FOR

ROUTINE ANALYSIS

SYSTEM SUMMARY

VACUUM SYSTEM	
	Sample analysis chamber (SAC)
	150 l/sec turbomolecular pump
	Base vacuum 5x10 ⁻⁷ Pa
	Sample introduction chamber
	50 l/sec turbomolecular pump
	10 sample introduction chamber (optional)
	System baking
	Integrated timer controlled heating tapes
SAMPLE HANDLING	
	10 sample carousel
	Fully software controlled
	Sample dimensions
	≤ 10 mm diameter
	≤ 5 mm thick
X-RAY SOURCE	
	Conical formed Mg target
	300W max power 12kV 25mA
	Dual Mg/Al anodes (optional)
ELECTRON ENERGY ANALYSER	
	Low pass/high pass filter
	Selectable pass energy 25, 75 and 150eV
	Single channeltron detector
ION ETCHING System	
	Standard ion etching source
	0.5, 1, 1.5 and 2 kV accelerating voltage
	Etch rate 5-100 Angstrom/min (material dependent)
	Sample rotation during etching
	Kaufman high speed etching source (option)
	0-1000 V accelerating voltage (continuously variable)
	Etch rate 50-800 Angstrom/min (material dependent)
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